# MEMS Innovation at Tohoku University



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From Tokyo to Sendai: 96 min Population of Sendai: 1 million Result of popularity vote in 2004 : 1st: Sapporo, 2nd: Shizuoka, 3rd: Sendai, 4th: Tokyo





 Tohoku Metal Industries Co., Ltd. (present: NEC TOKIN Corporation)

•Yagi Antenna Co., Ltd

(present: Hitachi Kokusai Electric Inc.)





#### TOHOKU UNIVERSITY Sendai, Japan

TOHOKU UNIVERSITY Sendai, Japan

# **Fundamental Policies**



- 1. "Research-intensive University"
  - as its mission
- 2. "Have University's doors open to the

World and Community"

#### as its principle

 "Development of Leading Human Resources"

as its educational goal







# **Overview of TOHOKU UNIVERSITY**

# **Research Paper Citations**

National Ranking	International Ranking	Field	Citations	Papers
1	3	Materials Science	27,139	4,782
2	9	Physics	101,289	10,390
4	18	Chemistry	59,753	5,935
2	36	Engineering	11,448	3,173
6	66	All Fields	337,898	38,371

Resource: ISI Essential Science Indicators<sup>SM</sup>, January 1, 1997 – February 28, 2007



# **Overview of TOHOKU UNIVERSITY**

# **Tohoku University US office**

- Supporting strategic application of research achievements to the world Supporting collaboration with overseas academia and international
- organizations (planning and holding symposium and seminar; developing collaborative researches and contract researches)
- ٠ Supporting cooperative educational opportunity with overseas academia and international organizations for symposium, distant learning, e-learning, short- and long-term overseas education
- Supporting Tohoku University Global Promotion Center ٠
  - Supporting formation of alumni organization in US and its activity
    - 4410 El Camino Real, suite #111, Los Altos, CA94022, USA



## What's MEMS

MEMS: Micro Electro Mechanical Systems

Tiny system combining electrical and mechanical components

Small and high performance sensor and actuator



ex.) Gyroscope, TOKIMEC, Japan 2-axis angular velocity and 3-axis acceleration Mechanical part 64mm silicon rotor Electrical part

Electrostatic levitation control rotation speed: 12,000 rpm

working as "the heart" or "the key" in a system



(Chemitronics)

# MEMS R&D facility at Tohoku University





120 m<sup>2</sup> MEMS clean room 400 users and 40 laboratories registered

Micro/Nanomachining Research and Education Center (MNC) 600 m<sup>2</sup> CMOS and MEMS clean room and evaluation facilities 500 users and 100 laboratories registered

2 cm x 2 cm, 2 and 4 inch facilities

More than 100 companies dispatched their researchers (full time)

### National project on MEMS at Tohoku University

Special Coordination Funds for Promoting Science and Technology

supported by MEXT (Japanese Ministry of Education, Science, culture, sports)

Formation of Innovation Center for Fusion of Advanced Technologies on;

#### Tohoku University R&D Center of Excellence for Integrated Microsystems

Term: 2007~2016 (Max.) Budget: ~\$70M

#### Concept R&D center based on open innovation Innovation Next generation industry-university linkage system · Human resource development beyond several fields Creative space for intelligent production Seeds of next generation industry Integrated microsystem technology Safety space for automobile Elec, Mech Optics Required technology Microsystem process for Hetero-system Chem. Material MEMS-LSI integration integration Bio nformatio Med. FUSION scale down limitation Microsystem LSI Technology technology



#### R&D Center of Excellence for Integrated Microsystems

(Formation of Innovation Center for Fusion of Advanced Technologies sponsored by Ministry of Education...) 2007~2009 (2016)

#### MEMS + LSI (SoC(System on Chip) & SiP(System in Package))







Arrayed MEMS, Capacitive sensors,

RF integrated MEMS, Disposable devices

#### Realize MEMS having good mechanical property on advanced small feature size LSI Problems to be solved :

O Low temperature processes (bonding or deposition) for MEMS having good mechanical properties for micromechanical resonator, switch etc..

O Damage-free and compatible processes (temperature, etching, electrostatic discharge etc.)

O Packaging, Test, Interconnection and so on.



Shuttle service shared in our project + Low temperature MEMS process







# Thank you for your attention!!



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